



Attorney's Docket No.: 42P17283

Patent

7/11/07

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Michael McSwiney et al.

U.S. Serial No: 10/750,062

Filed: December 30, 2003

For: METHOD AND APPARATUS FOR LOW
TEMPERATURE SILICON NITRIDE
DEPOSITION

Examiner: Turocy, David P.

Art Unit: 1762

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Signature Date

Commissioner of Patents and Trademarks
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RESPONSE TO SPECIES ELECTION

Sir:

In response to the Election Requirement mailed February 23, 2007, applicant(s) hereby elects to prosecute Group I claims 1-20, drawn to a method for depositing a silicon film. Additionally, Applicant elects Species A, the specific silicon precursor/source. It is Applicant's understanding that at least claims 1-11 and 13-20 are readable thereon. Accordingly, claims 21-27 are withdrawn from consideration.

If there are any additional charges, please charge Deposit Account No. 02-2666.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN

Date: July 11, 2007

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